















































































Elliptic patch Nuclear Localisation Screen



Image courtesy of J&J PRD





























Photometric reflection model										
$E(\lambda,x)=m(x)l(\lambda,x)c(\lambda,x)$										
assumption: $l(\lambda,x)=l(\lambda)$										
differentiation ($E = m l c$):										
$rac{\partial E}{\partial \lambda} = mc rac{\partial l}{\partial \lambda} + ml rac{\partial c}{\partial \lambda}$										
normalization:										
$rac{1}{E}rac{\partial E}{\partial\lambda} \;\;=\;\; rac{1}{l}rac{\partial l}{\partial\lambda}+rac{1}{c}rac{\partial c}{\partial\lambda}$										
and thus:										
$rac{\partial}{\partial x}\left\{rac{1}{E}rac{\partial E}{\partial\lambda} ight\} \;\;=\;\; rac{1}{c}rac{\partial^2 c}{\partial\lambda\partial x} - rac{1}{c^2}rac{\partial c}{\partial\lambda}rac{\partial c}{\partial x}$										
Courtesy of Jan-Mark Geusebroek										



		Hiera	rchy of	Invariar	nts
		Illumination Intensity	Shadow	H igh ligh ts	Illum in a tion Color
	Н	+	+	+	-
	Ν	+	+	_	+
	С	+	+	_	-
	W	+	-	-	-
	E	-	-	_	-
	•H is rela •N descr •C descr •W detei	ated to the Hue ibes object reflecta ibes object color re rmines changes in (nce independer gardless intens object reflectanc	nt of the illuminatio ity ce independent of	n illumination intensity
		Hierarchy of inv	ariants within $H \subset N = U \subset C$	the Kubelka-Mult $C \subset W \subset E$	nk model:
		J. M. Geusebroek, R. V IEEE T	van den Boomgaard, A. W. M. rans. Pattern Anal. Machine In	Smeulders, and H. Geerts. Color inv ttell., 23(12):1338-1350, 2001.	variance.
Courtesy	of Jan-Mark	Geusebroek			

































✓ Eazyx_measure							
Measurement Edit Help							
New Open Save SaveAs P	S IN All Mo	de 1 Mode 2 Mode 3	Mode 4 Mode 5 Help				
Measurement protocol							
None							
Mode 1	Mode 2		Mode 3	Mode 4	<u></u>	vlode 5	
Shape features			Intensity features	Extra features	No.		
🖌 Area. 📄 X max pos.	🗌 Y height	Short axis	O None O Trans	mission 🗌 Tubelength	Solidity	🗌 Neighbor dist	
Perimeter Y min pos.	🗌 X gravity cent	re 🔲 Long axis	🖲 Greyvalue 🔘 Optic	al Density 📝 Tubewidth	Elongation	Texture	
🗌 Contour ratio 🛛 🗌 Y max pos.	🗌 Y gravity cent	re 🔲 Eccentricity	Intensity parameters	Equiv. diamete	er 📝 Intensity min.	Reserved	
🗌 X min pos. 🗌 X width	🗌 Angle	Bending energy	I Mean ⊡ StD	Convexity	🗌 Intensity max.	Reserved	
			Min Ma	(
Carrier start	Image til	Image tile grouping X-axis					
1	12	3 1 3		0 0			
Carrier end	Image til	Image tile grouping Y-axis Image tiles overlap Y-axis					
	320 12	12 0					
Position start	Image til	Image tile grouping Z-axis Image tiles overlap Z-axis					
	1			÷ 1		1	
Position end	96						
Remove previous object masks	Reduction factor Garbage level (pixels) Pixel to micron conversion						
		1		U	v 1.00	13	







Conclusion	
 Framework designed for automated research Explore space, spectrum and time Distributed system for processing sample from image to data Applications in cytometry, tissue morphology and model organisms Automated image acquisition Superimages of arbitrary patterns Wide magnification range (1x,, 40x, 63x) Robust real-time automatic focus algorithm Combine space, spectrum and time at different scales Object detection Robust object shape detection Scale space Robust object color detection Spatial color model Object quantification Individual objects 	



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